

# Jordi Suñe

## List of Publications by Year in descending order

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295  
papers

6,871  
citations

71102

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85541

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300  
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300  
docs citations

300  
times ranked

3584  
citing authors

#	ARTICLE	IF	CITATIONS
1	Recommended Methods to Study Resistive Switching Devices. <i>Advanced Electronic Materials</i> , 2019, 5, 1800143.	5.1	452
2	Continuous Analytic $I$ - $V$ Model for Surrounding-Gate MOSFETs. <i>IEEE Electron Device Letters</i> , 2004, 25, 571-573.	3.9	254
3	New physics-based analytic approach to the thin-oxide breakdown statistics. <i>IEEE Electron Device Letters</i> , 2001, 22, 296-298.	3.9	249
4	On the breakdown statistics of very thin SiO <sub>2</sub> films. <i>Thin Solid Films</i> , 1990, 185, 347-362.	1.8	238
5	Quantum-size effects in hafnium-oxide resistive switching. <i>Applied Physics Letters</i> , 2013, 102, 183505.	3.3	151
6	Modeling of Nanoscale Gate-All-Around MOSFETs. <i>IEEE Electron Device Letters</i> , 2004, 25, 314-316.	3.9	136
7	Voltage and Power-Controlled Regimes in the Progressive Unipolar RESET Transition of HfO <sub>2</sub> -Based RRAM. <i>Scientific Reports</i> , 2013, 3, 2929.	3.3	135
8	Power-law voltage acceleration: A key element for ultra-thin gate oxide reliability. <i>Microelectronics Reliability</i> , 2005, 45, 1809-1834.	1.7	131
9	Experimental evidence of $T/\text{sub BD/}$ power-law for voltage dependence of oxide breakdown. <i>IEEE Transactions on Electron Devices</i> , 2002, 49, 2244-2253.	3.0	128
10	Standards for the Characterization of Endurance in Resistive Switching Devices. <i>ACS Nano</i> , 2021, 15, 17214-17231.	14.6	128
11	A Model for the Set Statistics of RRAM Inspired in the Percolation Model of Oxide Breakdown. <i>IEEE Electron Device Letters</i> , 2013, 34, 999-1001.	3.9	122
12	Electron transport through broken down ultra-thin SiO <sub>2</sub> layers in MOS devices. <i>Microelectronics Reliability</i> , 2004, 44, 1-23.	1.7	108
13	Quantum-mechanical modeling of accumulation layers in MOS structure. <i>IEEE Transactions on Electron Devices</i> , 1992, 39, 1732-1739.	3.0	103
14	Soft breakdown conduction in ultrathin (3-5 nm) gate dielectrics. <i>IEEE Transactions on Electron Devices</i> , 2000, 47, 82-89.	3.0	103
15	Cycle-to-Cycle Intrinsic RESET Statistics in $\text{HfO}_2$ -Based Unipolar RRAM Devices. <i>IEEE Electron Device Letters</i> , 2013, 34, 623-625.	3.9	101
16	Interplay of voltage and temperature acceleration of oxide breakdown for ultra-thin gate oxides. <i>Solid-State Electronics</i> , 2002, 46, 1787-1798.	1.4	99
17	Analysis and modeling of resistive switching statistics. <i>Journal of Applied Physics</i> , 2012, 111, .	2.5	97
18	Exploratory observations of post-breakdown conduction in polycrystalline silicon and metal-gated thin-oxide metal-oxide-semiconductor capacitors. <i>Journal of Applied Physics</i> , 1993, 73, 205-215.	2.5	95

#	ARTICLE	IF	CITATIONS
19	On the weibull shape factor of intrinsic breakdown of dielectric films and its accurate experimental determination-part II: experimental results and the effects of stress conditions. IEEE Transactions on Electron Devices, 2002, 49, 2141-2150.	3.0	87
20	Self-consistent solution of the Poisson and Schrödinger equations in accumulated semiconductor-insulator interfaces. Journal of Applied Physics, 1991, 70, 337-345.	2.5	82
21	Conductance Quantization in Resistive Random Access Memory. Nanoscale Research Letters, 2015, 10, 420.	5.7	81
22	Unified compact model for the ballistic quantum wire and quantum well metal-oxide-semiconductor field-effect-transistor. Journal of Applied Physics, 2003, 94, 1061-1068.	2.5	77
23	A function-fit model for the soft breakdown failure mode. IEEE Electron Device Letters, 1999, 20, 265-267.	3.9	76
24	Transport properties of oxygen vacancy filaments in metal/crystalline or amorphous HfO <sub>2</sub> /metal structures. Physical Review B, 2012, 86, .	3.2	70
25	Statistics of successive breakdown events in gate oxides. IEEE Electron Device Letters, 2003, 24, 272-274.	3.9	69
26	Hydrogen-Release Mechanisms in the Breakdown of ThinSiO <sub>2</sub> Films. Physical Review Letters, 2004, 92, 087601.	7.8	68
27	Reset Statistics of NiO-Based Resistive Switching Memories. IEEE Electron Device Letters, 2011, 32, 1570-1572.	3.9	68
28	Are soft breakdown and hard breakdown of ultrathin gate oxides actually different failure mechanisms?. IEEE Electron Device Letters, 2000, 21, 167-169.	3.9	65
29	Many-particle Hamiltonian for open systems with full Coulomb interaction: Application to classical and quantum time-dependent simulations of nanoscale electron devices. Physical Review B, 2009, 79, .	3.2	62
30	Simulation of thermal reset transitions in resistive switching memories including quantum effects. Journal of Applied Physics, 2014, 115, .	2.5	61
31	Soft breakdown fluctuation events in ultrathin SiO <sub>2</sub> layers. Applied Physics Letters, 1998, 73, 490-492.	3.3	60
32	An in-depth simulation study of thermal reset transitions in resistive switching memories. Journal of Applied Physics, 2013, 114, .	2.5	58
33	Engineering of the Chemical Reactivity of the Ti/HfO <sub>2</sub> Interface for RRAM: Experiment and Theory.. ACS Applied Materials & Interfaces, 2014, 6, 5056-5060.	8.0	55
34	Multi-scale quantum point contact model for filamentary conduction in resistive random access memories devices. Journal of Applied Physics, 2014, 115, .	2.5	54
35	Implications of the noncrossing property of Bohm trajectories in one-dimensional tunneling configurations. Physical Review A, 1996, 54, 2594-2604.	2.5	53
36	Impact of Intercell and Intracell Variability on Forming and Switching Parameters in RRAM Arrays. IEEE Transactions on Electron Devices, 2015, 62, 2502-2509.	3.0	52

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37	The Quantum Point-Contact Memristor. IEEE Electron Device Letters, 2012, 33, 1474-1476.	3.9	46
38	\$\$\{ SIM\}^2\{ RRAM\}\$\$ S I M 2 R R A M : a physical model for RRAM devices simulation. Journal of Computational Electronics, 2017, 16, 1095-1120.	2.5	45
39	Degradation and Breakdown of Gate Oxides in VLSI Devices. Physica Status Solidi A, 1989, 111, 675-685.	1.7	44
40	Nonlinear conductance quantization effects in CeOx/SiO2-based resistive switching devices. Applied Physics Letters, 2012, 101, .	3.3	43
41	A new compact model for bipolar RRAMs based on truncated-cone conductive filamentsâ€”a Verilog-A approach. Semiconductor Science and Technology, 2016, 31, 115013.	2.0	43
42	Set statistics in conductive bridge random access memory device with Cu/HfO2/Pt structure. Applied Physics Letters, 2014, 105, .	3.3	42
43	Modeling the breakdown spots in silicon dioxide films as point contacts. Applied Physics Letters, 1999, 75, 959-961.	3.3	41
44	Analytical Cell-Based Model for the Breakdown Statistics of Multilayer Insulator Stacks. IEEE Electron Device Letters, 2009, 30, 1359-1361.	3.9	41
45	An in-depth study of thermal effects in reset transitions in HfO2 based RRAMs. Solid-State Electronics, 2015, 111, 47-51.	1.4	41
46	Point contact conduction at the oxide breakdown of MOS devices. , 0, , .		40
47	On the Thermal Models for Resistive Random Access Memory Circuit Simulation. Nanomaterials, 2021, 11, 1261.	4.1	39
48	Successive Oxide Breakdown Statistics: Correlation Effects, Reliability Methodologies, and Their Limits. IEEE Transactions on Electron Devices, 2004, 51, 1584-1592.	3.0	37
49	Analog performance of the nanoscale double-gate metal-oxide-semiconductor field-effect-transistor near the ultimate scaling limits. Journal of Applied Physics, 2004, 96, 5271-5276.	2.5	35
50	Improving resistance uniformity and endurance of resistive switching memory by accurately controlling the stress time of pulse program operation. Applied Physics Letters, 2015, 106, .	3.3	35
51	Analytic modeling of leakage current through multiple breakdown paths in SiO/sub 2/ films. , 0, , .		34
52	Statistics of competing post-breakdown failure modes in ultrathin MOS devices. IEEE Transactions on Electron Devices, 2006, 53, 224-234.	3.0	34
53	Modeling Transport in Ultrathin Si Nanowires: Charged versus Neutral Impurities. Nano Letters, 2008, 8, 2825-2828.	9.1	34
54	Trapped charge distributions in thin (10 nm) SiO/sub 2/ films subjected to static and dynamic stresses. IEEE Transactions on Electron Devices, 1998, 45, 881-888.	3.0	33

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55	Time-dependent boundary conditions with lead-sample Coulomb correlations: Application to classical and quantum nanoscale electron device simulators. <i>Physical Review B</i> , 2010, 82, .	3.2	32
56	Determination of the Si-SiO <sub>2</sub> / barrier height from the Fowler-Nordheim plot. <i>IEEE Electron Device Letters</i> , 1991, 12, 620-622.	3.9	31
57	A comprehensive analysis on progressive reset transitions in RRAMs. <i>Journal Physics D: Applied Physics</i> , 2014, 47, 205102.	2.8	31
58	Voltage-Driven Hysteresis Model for Resistive Switching: SPICE Modeling and Circuit Applications. <i>IEEE Transactions on Computer-Aided Design of Integrated Circuits and Systems</i> , 2017, 36, 2044-2051.	2.7	31
59	Resistive switching in CeO <sub>2</sub> /La <sub>0.8</sub> Sr <sub>0.2</sub> MnO <sub>3</sub> bilayer for non-volatile memory applications. <i>Microelectronic Engineering</i> , 2015, 147, 37-40.	2.4	30
60	New insights in polarity-dependent oxide breakdown for ultrathin gate oxide. <i>IEEE Electron Device Letters</i> , 2002, 23, 494-496.	3.9	29
61	A Compact Model for Oxide Breakdown Failure Distribution in Ultrathin Oxides Showing Progressive Breakdown. <i>IEEE Electron Device Letters</i> , 2008, 29, 949-951.	3.9	29
62	Investigation on the RESET switching mechanism of bipolar Cu/HfO <sub>2</sub> /Pt RRAM devices with a statistical methodology. <i>Journal Physics D: Applied Physics</i> , 2013, 46, 245107.	2.8	29
63	Memristors for Neuromorphic Circuits and Artificial Intelligence Applications. <i>Materials</i> , 2020, 13, 938.	2.9	29
64	Advanced electrical-level modeling of EEPROM cells. <i>IEEE Transactions on Electron Devices</i> , 1993, 40, 951-957.	3.0	27
65	Degradation and breakdown of thin silicon dioxide films under dynamic electrical stress. <i>IEEE Transactions on Electron Devices</i> , 1996, 43, 2215-2226.	3.0	27
66	Statistics of successive breakdown events for ultra-thin gate oxides. , 0, , .		27
67	Critical reliability challenges in scaling SiO <sub>2</sub> -based dielectric to its limit. <i>Microelectronics Reliability</i> , 2003, 43, 1175-1184.	1.7	26
68	Volume Resistive Switching in metallic perovskite oxides driven by the Metal-Insulator Transition. <i>Journal of Electroceramics</i> , 2017, 39, 185-196.	2.0	26
69	Analysis and simulation of the multiple resistive switching modes occurring in HfO <sub>x</sub> -based resistive random access memories using memdiodes. <i>Journal of Applied Physics</i> , 2019, 125, .	2.5	26
70	Understanding soft and hard breakdown statistics, prevalence ratios and energy dissipation during breakdown runaway. , 0, , .		25
71	Detection and fitting of the soft breakdown failure mode in MOS structures. <i>Solid-State Electronics</i> , 1999, 43, 1801-1805.	1.4	24
72	Resistive Switching with Self-Rectifying Tunability and Influence of the Oxide Layer Thickness in Ni/HfO <sub>2</sub> /n <sup>+</sup> -Si RRAM Devices. <i>IEEE Transactions on Electron Devices</i> , 2017, 64, 3159-3166.	3.0	24

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73	Temperature dependence of Fowler-Nordheim injection from accumulated n-type silicon into silicon dioxide. IEEE Transactions on Electron Devices, 1993, 40, 1017-1019.	3.0	23
74	Comprehensive physics-based breakdown model for reliability assessment of oxides with thickness ranging from 1 nm up to 12 nm. Reliability Physics Symposium, 2009 IEEE International, 2009, , .	0.0	23
75	Equivalent circuit modeling of the bistable conduction characteristics in electroformed thin dielectric films. Microelectronics Reliability, 2015, 55, 1-14.	1.7	21
76	An in-depth description of bipolar resistive switching in Cu/HfO <sub>x</sub> /Pt devices, a 3D kinetic Monte Carlo simulation approach. Journal of Applied Physics, 2018, 123, .	2.5	21
77	Nondestructive multiple breakdown events in very thin SiO <sub>2</sub> films. Applied Physics Letters, 1989, 55, 128-130.	3.3	20
78	Soft Breakdown in Ultrathin SiO <sub>2</sub> Layers: the Conduction Problem from a New Point of View. Japanese Journal of Applied Physics, 1999, 38, 2223-2226.	1.5	20
79	Monitoring the degradation that causes the breakdown of ultrathin (<5 nm) SiO <sub>2</sub> gate oxides. IEEE Electron Device Letters, 2000, 21, 251-253.	3.9	20
80	Failure physics of ultra-thin SiO <sub>2</sub> gate oxides near their scaling limit. Semiconductor Science and Technology, 2000, 15, 445-454.	2.0	20
81	Multilevel recording in Bi-deficient Pt/BFO/SRO heterostructures based on ferroelectric resistive switching targeting high-density information storage in nonvolatile memories. Applied Physics Letters, 2013, 103, .	3.3	20
82	Investigation on the Conductive Filament Growth Dynamics in Resistive Switching Memory via a Universal Monte Carlo Simulator. Scientific Reports, 2017, 7, 11204.	3.3	20
83	Switching Voltage and Time Statistics of Filamentary Conductive Paths in HfO <sub>2</sub> -Based ReRAM Devices. IEEE Electron Device Letters, 2018, 39, 656-659.	3.9	20
84	SPICE Implementation of the Dynamic Memdiode Model for Bipolar Resistive Switching Devices. Micromachines, 2022, 13, 330.	2.9	20
85	Breakdown of thin gate silicon dioxide films—A review. Microelectronics Reliability, 1996, 36, 871-905.	1.7	19
86	The effects of device dimensions on the post-breakdown characteristics of ultrathin gate oxides. IEEE Electron Device Letters, 2005, 26, 401-403.	3.9	19
87	Multi-channel conduction in redox-based resistive switch modelled using quantum point contact theory. Applied Physics Letters, 2013, 103, .	3.3	19
88	Application of the Quasi-Static Memdiode Model in Cross-Point Arrays for Large Dataset Pattern Recognition. IEEE Access, 2020, 8, 202174-202193.	4.2	19
89	Post soft breakdown conduction in SiO <sub>2</sub> gate oxides. , 0, , .		18
90	Approach to study the noise properties in nanoscale electronic devices. Applied Physics Letters, 2001, 79, 1703-1705.	3.3	18

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91	On the progressive breakdown statistical distribution and its voltage acceleration. , 2007, , .		18
92	On Voltage Acceleration Models of Time to Breakdownâ€”Part I: Experimental and Analysis Methodologies. IEEE Transactions on Electron Devices, 2009, , .	3.0	18
93	Characterization of HfO <sub>2</sub> -based devices with indication of second order memristor effects. Microelectronic Engineering, 2018, 195, 101-106.	2.4	18
94	Engineering Oxygen Migration for Homogeneous Volume Resistive Switching in 3â€”Terminal Devices. Advanced Electronic Materials, 2019, 5, 1800629.	5.1	18
95	Characterization of SiO <sub>2</sub> /sub 2/ dielectric breakdown for reliability simulation. IEEE Transactions on Electron Devices, 1993, 40, 1662-1668.	3.0	17
96	A novel approach to quantum point contact for post soft breakdown conduction. , 0, , .		17
97	Mesoscopic approach to the soft breakdown failure mode in ultrathin SiO <sub>2</sub> films. Applied Physics Letters, 2001, 78, 225-227.	3.3	17
98	Post-radiation-induced soft breakdown conduction properties as a function of temperature. Applied Physics Letters, 2001, 79, 1336-1338.	3.3	17
99	Polarity-dependent oxide breakdown of NFET devices for ultra-thin gate oxide. , 0, , .		17
100	Successive breakdown events and their relation with soft and hard breakdown modes. IEEE Electron Device Letters, 2003, 24, 692-694.	3.9	17
101	Initial leakage current related to extrinsic breakdown in HfO <sub>2</sub> /Al <sub>2</sub> O <sub>3</sub> nanolaminate ALD dielectrics. Microelectronic Engineering, 2011, 88, 1380-1383.	2.4	17
102	Generalized hydrogen release-reaction model for the breakdown of modern gate dielectrics. Journal of Applied Physics, 2013, 114, .	2.5	17
103	Electrochemical Tuning of Metal Insulator Transition and Nonvolatile Resistive Switching in Superconducting Films. ACS Applied Materials & Interfaces, 2018, 10, 30522-30531.	8.0	17
104	Oscillatory bohm trajectories in resonant tunneling structures. Solid State Communications, 1996, 99, 123-128.	1.9	16
105	Bohm trajectories for the Monte Carlo simulation of quantum-based devices. Applied Physics Letters, 1998, 72, 806-808.	3.3	16
106	Modeling the breakdown and breakdown statistics of ultra-thin SiO <sub>2</sub> gate oxides. Microelectronic Engineering, 2001, 59, 149-153.	2.4	16
107	Statistical characteristics of reset switching in Cu/HfO <sub>2</sub> /Pt resistive switching memory. Nanoscale Research Letters, 2014, 9, 2500.	5.7	16
108	Modeling the conduction characteristics of broken down gate oxides in MOS structures. Microelectronics Reliability, 2000, 40, 1599-1603.	1.7	15

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109	High frequency components of current fluctuations in semiconductor tunneling barriers. Applied Physics Letters, 2002, 80, 4048-4050.	3.3	15
110	Statistics of soft and hard breakdown in thin SiO <sub>2</sub> gate oxides. Microelectronics Reliability, 2003, 43, 1185-1192.	1.7	15
111	Critical assessment of soft breakdown stability time and the implementation of new post-breakdown methodology for ultra-thin gate oxides [MOSFET]. , 0, , .		15
112	Modeling the breakdown statistics of Al <sub>2</sub> O <sub>3</sub> /HfO <sub>2</sub> nanolaminates grown by atomic-layer-deposition. Solid-State Electronics, 2012, 71, 48-52.	1.4	15
113	A Physical Model for the Statistics of the Set Switching Time of Resistive RAM Measured With the Width-Adjusting Pulse Operation Method. IEEE Electron Device Letters, 2015, 36, 1303-1306.	3.9	15
114	Effect of the voltage ramp rate on the set and reset voltages of ReRAM devices. Microelectronic Engineering, 2017, 178, 61-65.	2.4	15
115	Quantum Monte Carlo simulation of resonant tunneling diodes based on the Wigner distribution function formalism. Applied Physics Letters, 1998, 73, 3539-3541.	3.3	14
116	Switching behavior of the soft breakdown conduction characteristic in ultra-thin (<5 nm) oxide MOS capacitors. , 1998, , .		14
117	Quantitative two-step hydrogen model of SiO <sub>2</sub> gate oxide breakdown. Solid-State Electronics, 2002, 46, 1825-1837.	1.4	14
118	A strong analogy between the dielectric breakdown of high-K gate stacks and the progressive breakdown of ultrathin oxides. Journal of Applied Physics, 2011, 109, 124115.	2.5	14
119	Threshold Switching and Conductance Quantization in Al/HfO <sub>2</sub> /Si(p) Structures. Japanese Journal of Applied Physics, 2013, 52, 04CD06.	1.5	14
120	Memristive State Equation for Bipolar Resistive Switching Devices Based on a Dynamic Balance Model and Its Equivalent Circuit Representation. IEEE Nanotechnology Magazine, 2020, 19, 837-840.	2.0	14
121	On the dissipation of energy by hot electrons in SiO <sub>2</sub> . Journal Physics D: Applied Physics, 1990, 23, 1576-1581.	2.8	13
122	Analysis of the degradation and breakdown of thin SiO <sub>2</sub> films under static and dynamic tests using a two-step stress procedure. IEEE Transactions on Electron Devices, 2000, 47, 2138-2145.	3.0	13
123	BREAKDOWN MODES AND BREAKDOWN STATISTICS OF ULTRATHIN SiO <sub>2</sub> GATE OXIDES. International Journal of High Speed Electronics and Systems, 2001, 11, 789-848.	0.7	13
124	A comprehensive investigation of gate oxide breakdown of P+Poly/PFETs under inversion mode. , 0, , .		13
125	A physics-based deconstruction of the percolation model of oxide breakdown. Microelectronic Engineering, 2007, 84, 1917-1920.	2.4	13
126	Boundary conditions with Pauli exclusion and charge neutrality: application to the Monte Carlo simulation of ballistic nanoscale devices. Journal of Computational Electronics, 2008, 7, 213-216.	2.5	13



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127	Modeling of hysteretic Schottky diode-like conduction in Pt/BiFeO <sub>3</sub> /SrRuO <sub>3</sub> switches. Applied Physics Letters, 2014, 105, .	3.3	13
128	Temperature and polarity dependence of the switching behavior of Ni/HfO <sub>2</sub> -based RRAM devices. Microelectronic Engineering, 2015, 147, 75-78.	2.4	13
129	Analysis on the Filament Structure Evolution in Reset Transition of Cu/HfO <sub>2</sub> /Pt RRAM Device. Nanoscale Research Letters, 2016, 11, 269.	5.7	13
130	A New Perspective Towards the Understanding of the Frequency-Dependent Behavior of Memristive Devices. IEEE Electron Device Letters, 2021, 42, 565-568.	3.9	13
131	Towards the Monte Carlo simulation of resonant tunnelling diodes using time-dependent wavepackets and Bohm trajectories. Semiconductor Science and Technology, 1999, 14, 532-542.	2.0	12
132	Interplay of voltage and temperature acceleration of oxide breakdown for ultra-thin oxides. Microelectronic Engineering, 2001, 59, 25-31.	2.4	12
133	Degradation analysis and characterization of multifilamentary conduction patterns in high-field stressed atomic-layer-deposited TiO <sub>2</sub> /Al <sub>2</sub> O <sub>3</sub> nanolaminates on GaAs. Journal of Applied Physics, 2012, 112, 064113.	2.5	12
134	Study on the Connection Between the Set Transient in RRAMs and the Progressive Breakdown of Thin Oxides. IEEE Transactions on Electron Devices, 2019, 66, 3349-3355.	3.0	12
135	Transient simulation of the ERASE cycle of floating gate EEPROMs. , 0, , .		11
136	Reversible dielectric breakdown of thin gate oxides in MOS devices. Microelectronics Reliability, 1993, 33, 1031-1039.	1.7	11
137	Effects of spacer layers on the Wigner function simulation of resonant tunneling diodes. Journal of Applied Physics, 1998, 83, 8057-8061.	2.5	11
138	Switching events in the soft breakdown $I_{\text{set}}$ characteristic of ultra-thin SiO <sub>2</sub> layers. Microelectronics Reliability, 1999, 39, 161-164.	1.7	11
139	A new approach to analyze the degradation and breakdown of thin SiO <sub>2</sub> films under static and dynamic electrical stress. IEEE Electron Device Letters, 1999, 20, 317-319.	3.9	11
140	Gate stack insulator breakdown when the interface layer thickness is scaled toward zero. Applied Physics Letters, 2010, 97, .	3.3	11
141	A compact analytic model for the breakdown distribution of gate stack dielectrics. , 2010, , .		11
142	Minimization of the Line Resistance Impact on Memdiode-Based Simulations of Multilayer Perceptron Arrays Applied to Pattern Recognition. Journal of Low Power Electronics and Applications, 2021, 11, 9.	2.0	11
143	On the SiO <sub>x</sub> transition layer in abrupt Si-SiO <sub>2</sub> chemical interface in MOS structures. Surface Science, 1989, 208, 463-472.	1.9	10
144	Comparison between the relaxation time approximation and the Boltzmann collision operator for simulation of dissipative electron transport in resonant tunnelling diodes. Solid-State Electronics, 1996, 39, 1795-1804.	1.4	10

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145	Relation between defect generation, stress induced leakage current and soft breakdown in thin (<5) Tj ETQq1 1 0.784314 rgBT /Over	1.7	10
146	Quantum point contact model of filamentary conduction in resistive switching memories. , 2012, , .		10
147	Three-state resistive switching in HfO2-based RRAM. Solid-State Electronics, 2014, 98, 38-44.	1.4	10
148	Characterization of the metal-SiO2-Si interface roughness by electrical methods. Surface Science, 1987, 189-190, 346-352.	1.9	9
149	A common framework for soft and hard breakdown in ultrathin oxides based on the theory of point contact conduction. Microelectronic Engineering, 1999, 48, 171-174.	2.4	9
150	Comment on "Quantum Wave Packet Dynamics with Trajectories" Physical Review Letters, 2000, 85, 894-894.	7.8	9
151	A simple drain current model for Schottky-barrier carbon nanotube field effect transistors. Nanotechnology, 2007, 18, 419001.	2.6	9
152	On Voltage Acceleration Models of Time to Breakdown"Part II: Experimental Results and Voltage Dependence of Weibull Slope in the FN Regime. IEEE Transactions on Electron Devices, 2009, , .	3.0	9
153	Accurate Calculation of Gate Tunneling Current in Double-Gate and Single-Gate SOI MOSFETs Through Gate Dielectric Stacks. IEEE Transactions on Electron Devices, 2012, 59, 2589-2596.	3.0	9
154	Explicit model for the gate tunneling current in double-gate MOSFETs. Solid-State Electronics, 2012, 68, 93-97.	1.4	9
155	Nonhomogeneous spatial distribution of filamentary leakage current paths in circular area Pt/HfO2/Pt capacitors. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2013, 31, 01A107.	1.2	9
156	Modeling of the multilevel conduction characteristics and fatigue profile of Ag/La1/3Ca2/3MnO3/Pt structures using a compact memristive approach. Journal of Applied Physics, 2017, 121, .	2.5	9
157	A cell-based clustering model for the reset statistics in RRAM. Applied Physics Letters, 2017, 110, .	3.3	9
158	Weibull slopes, critical defect density, and the validity of stress-induced-leakage current (SILC) measurements. , 0, , .		8
159	Ordered arrays of quantum wires through hole patterning: ab initio and empirical electronic structure calculations. Applied Physics Letters, 2007, 90, 083118.	3.3	8
160	Many-particle transport in the channel of quantum wire double-gate field-effect transistors with charged atomistic impurities. Journal of Applied Physics, 2010, 108, 043706.	2.5	8
161	Analysis of the breakdown spot spatial distribution in Pt/HfO2/Pt capacitors using nearest neighbor statistics. Journal of Applied Physics, 2013, 114, 154112.	2.5	8
162	The statistical distribution of breakdown from multiple breakdown events in one sample. Journal Physics D: Applied Physics, 1991, 24, 407-414.	2.8	7

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163	Stationary modeling of two-dimensional states in resonant tunneling devices. Journal of Applied Physics, 1995, 78, 2135-2137.	2.5	7
164	Hydrogen desorption in SiGe films: A diffusion limited process. Applied Physics Letters, 1997, 70, 3287-3289.	3.3	7
165	Conduction properties of breakdown paths in ultrathin gate oxides. Microelectronics Reliability, 2000, 40, 687-690.	1.7	7
166	Limits of the successive breakdown statistics to assess chip reliability. Microelectronic Engineering, 2004, 72, 39-44.	2.4	7
167	Statistical and voltage scaling properties of post-breakdown for ultra-thin-oxide PFETs in inversion mode. , 2006, , .		7
168	Explicit quantum potential and charge model for double-gate MOSFETs. Solid-State Electronics, 2010, 54, 530-535.	1.4	7
169	Multiple Diode-Like Conduction in Resistive Switching SiO <sub>2</sub> -Based MIM Devices. IEEE Nanotechnology Magazine, 2015, 14, 15-17.	2.0	7
170	Identification of the generation/rupture mechanism of filamentary conductive paths in ReRAM devices using oxide failure analysis. Microelectronics Reliability, 2017, 76-77, 178-183.	1.7	7
171	Exploratory study and application of the angular wavelet analysis for assessing the spatial distribution of breakdown spots in Pt/HfO <sub>2</sub> /Pt structures. Journal of Applied Physics, 2017, 122, 215304.	2.5	7
172	Relation between degradation and breakdown of thin SiO <sub>2</sub> films under AC stress conditions. Microelectronic Engineering, 1995, 28, 321-324.	2.4	6
173	Breakdown and anti-breakdown events in high-field stressed ultrathin gate oxides. Solid-State Electronics, 2001, 45, 1327-1332.	1.4	6
174	Temperature-dependent transition to progressive breakdown in thin silicon dioxide based gate dielectrics. Applied Physics Letters, 2005, 86, 193502.	3.3	6
175	A drain current model for Schottky-barrier CNT-FETs. Journal of Computational Electronics, 2007, 5, 361-364.	2.5	6
176	Failure-current based oxide reliability assessment methodology. , 2008, , .		6
177	Post-breakdown statistics and acceleration characteristics in high-K dielectric stacks. , 2011, , .		6
178	Modeling of the switching I-V characteristics in ultrathin (5Å) atomic layer deposited HfO <sub>2</sub> films using the logistic hysteron. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2015, 33, 01A102.	1.2	6
179	A thorough investigation of the progressive reset dynamics in HfO <sub>2</sub> -based resistive switching structures. Applied Physics Letters, 2015, 107, 113507.	3.3	6
180	Equivalent circuit model for the electron transport in 2D resistive switching material systems. , 2017, , .		6

#	ARTICLE	IF	CITATIONS
181	SPICE simulation of memristive circuits based on memdiodes with sigmoidal threshold functions. International Journal of Circuit Theory and Applications, 2018, 46, 39-49.	2.0	6
182	SPICE model for the current-voltage characteristic of resistive switching devices including the snapback effect. Microelectronic Engineering, 2019, 215, 110998.	2.4	6
183	Application of the Clustering Model to Time-Correlated Oxide Breakdown Events in Multilevel Antifuse Memory Cells. IEEE Electron Device Letters, 2020, 41, 1770-1773.	3.9	6
184	After-breakdown conduction through ultrathin SiO <sub>2</sub> films in metal/insulator/semiconductor structures. Thin Solid Films, 1991, 196, 11-27.	1.8	5
185	Quantum effects in accumulated MOS thin dielectric structures. Microelectronics Journal, 1994, 25, 523-531.	2.0	5
186	Analysis of the evolution of the trapped charge distributions in 10nm SiO <sub>2</sub> films during DC and bipolar dynamic stress. Microelectronics Reliability, 1997, 37, 1517-1520.	1.7	5
187	Coupling between the Liouville equation and a classical Monte Carlo solver for the simulation of electron transport in resonant tunneling diodes. Solid-State Electronics, 1999, 43, 315-323.	1.4	5
188	Post-Breakdown Characteristics of Extrinsic Failure Modes for Ultra-Thin Gate Oxides. , 2006, , .		5
189	Compact analytical models for the SET and RESET switching statistics of RRAM inspired in the cell-based percolation model of gate dielectric breakdown. , 2013, , .		5
190	Recent advances in dielectric breakdown of modern gate dielectrics. , 2013, , .		5
191	Failure Analysis of MIM and MIS Structures Using Point-to-Event Distance and Angular Probability Distributions. IEEE Transactions on Device and Materials Reliability, 2014, 14, 1080-1090.	2.0	5
192	Assessing the spatial correlation and conduction state of breakdown spot patterns in Pt/HfO <sub>2</sub> /Pt structures using transient infrared thermography. Journal of Applied Physics, 2014, 115, 174502.	2.5	5
193	SPICE Simulation of RRAM-Based Cross-Point Arrays Using the Dynamic Memdiode Model. Frontiers in Physics, 2021, 9, .	2.1	5
194	High field dynamic stress of thin SiO <sub>2</sub> films. Microelectronics Reliability, 1995, 35, 539-553.	1.7	4
195	Two-step stress methodology for monitoring the gate oxide degradation in MOS devices. Solid-State Electronics, 2001, 45, 1317-1325.	1.4	4
196	BREAKDOWN MODES AND BREAKDOWN STATISTICS OF ULTRATHIN SiO <sub>2</sub> GATE OXIDES. Selected Topics in Electornics and Systems, 2002, , 173-232.	0.2	4
197	Impact of stress induced leakage current on power-consumption in ultra-thin gate oxides. , 0, , .		4
198	Critical evaluation of hard-breakdown based reliability methodologies for ultrathin gate oxides. Microelectronic Engineering, 2004, 72, 16-23.	2.4	4

#	ARTICLE	IF	CITATIONS
199	A viable and comprehensive TDDDB assessment methodology for investigation of SRAM $V_{\min}$ failure. , 2009, , .		4
200	Modeling the breakdown statistics of gate dielectric stacks including percolation and progressive breakdown. , 2010, , .		4
201	From dielectric failure to memory function: Learning from oxide breakdown for improved understanding of resistive switching memories. , 2011, , .		4
202	On the properties of conducting filament in ReRAM. , 2014, , .		4
203	Model for the Current-Voltage Characteristic of Resistive Switches Based on Recursive Hysteretic Operators. IEEE Electron Device Letters, 2015, 36, 944-946.	3.9	4
204	Spatial analysis of failure sites in large area MIM capacitors using wavelets. Microelectronic Engineering, 2017, 178, 10-16.	2.4	4
205	SPICE simulation of 1T1R structures based on a logistic hysteresis operator. , 2017, , .		4
206	A new method for estimating the conductive filament temperature in OxRAM devices based on escape rate theory. Microelectronics Reliability, 2018, 88-90, 142-146.	1.7	4
207	Assessing the Correlation Between Location and Size of Catastrophic Breakdown Events in High-K MIM Capacitors. IEEE Transactions on Device and Materials Reliability, 2019, 19, 452-460.	2.0	4
208	Gate oxide breakdown statistics in wearout tests of metal-oxide-semiconductor structures. Microelectronics Journal, 1989, 20, 27-39.	2.0	3
209	Non-equilibrium gate tunneling current in ultra-thin (<2 nm) oxide MOS devices. Journal of Non-Crystalline Solids, 2001, 280, 127-131.	3.1	3
210	Progressive breakdown dynamics and entropy production in ultrathin SiO <sub>2</sub> gate oxides. Applied Physics Letters, 2011, 98, .	3.3	3
211	From post-breakdown conduction to resistive switching effect in thin dielectric films. , 2012, , .		3
212	Direct observation of the generation of breakdown spots in MIM structures under constant voltage stress. Microelectronics Reliability, 2013, 53, 1257-1260.	1.7	3
213	Analysis and Simulation of the Postbreakdown $I$ - $V$ Characteristics of n-MOS Transistors in the Linear Response Regime. IEEE Electron Device Letters, 2013, 34, 798-800.	3.9	3
214	Breakdown time statistics of successive failure events in constant voltage-stressed Al <sub>2</sub> O <sub>3</sub> /HfO <sub>2</sub> nanolaminates. Microelectronic Engineering, 2015, 147, 85-88.	2.4	3
215	Electrical characterization of multiple leakage current paths in HfO <sub>2</sub> /Al <sub>2</sub> O <sub>3</sub> -based nanolaminates. Microelectronics Reliability, 2015, 55, 1442-1445.	1.7	3
216	SPICE model for the ramp rate effect in the reset characteristic of memristive devices. , 2017, , .		3

#	ARTICLE	IF	CITATIONS
217	Characterization of the Failure Site Distribution in MIM Devices Using Zoomed Wavelet Analysis. Journal of Electronic Materials, 2018, 47, 5033-5038.	2.2	3
218	On the Application of a Diffusive Memristor Compact Model to Neuromorphic Circuits. Materials, 2019, 12, 2260.	2.9	3
219	Detection of inhibitory effects in the generation of breakdown spots in HfO <sub>2</sub> -based MIM devices. Microelectronic Engineering, 2019, 215, 111023.	2.4	3
220	Multi-Terminal Transistor-Like Devices Based on Strongly Correlated Metallic Oxides for Neuromorphic Applications. Materials, 2020, 13, 281.	2.9	3
221	Tunability Properties and Compact Modeling of HfO <sub>2</sub> -Based Complementary Resistive Switches Using a Three-Terminal Subcircuit. IEEE Transactions on Electron Devices, 2021, , 1-8.	3.0	3
222	Assessment and Improvement of the Pattern Recognition Performance of Memdiode-Based Cross-Point Arrays with Randomly Distributed Stuck-at-Faults. Electronics (Switzerland), 2021, 10, 2427.	3.1	3
223	Analysis of the successive breakdown statistics of multilayer Al <sub>2</sub> O <sub>3</sub> /HfO <sub>2</sub> gate stacks using the time-dependent clustering model. Microelectronics Reliability, 2020, 114, 113748.	1.7	3
224	The Thermal Growth of Very Thin SiO <sub>2</sub> Films A Diffusion-Controlled Process. Physica Status Solidi A, 1989, 114, 167-175.	1.7	2
225	Bohm trajectories for the modeling of tunneling devices. Microelectronic Engineering, 1997, 36, 125-128.	2.4	2
226	Linear and non-linear conduction regimes in broken down gate oxides. Journal of Non-Crystalline Solids, 2001, 280, 132-137.	3.1	2
227	Compact modeling of nanoscale MOSFETs in the ballistic limit. , 0, , .		2
228	Simulation of the time-dependent breakdown characteristics of heavy-ion irradiated gate oxides using a mean-reverting Poisson-Gaussian process. IEEE Transactions on Nuclear Science, 2005, 52, 1462-1467.	2.0	2
229	Physics-based model of the surrounding-gate MOSFET. , 0, , .		2
230	Spin-dependent injection model for Monte Carlo device simulation. Journal of Applied Physics, 2008, 104, .	2.5	2
231	Relating Extrinsic Breakdown Statistics to the Initial Current Leakage Distribution in Gate Oxides. ECS Transactions, 2010, 27, 243-248.	0.5	2
232	High-K dielectric stack percolation breakdown statistics. , 2010, , .		2
233	Cell-based models for the switching statistics of RRAM. , 2011, , .		2
234	Explicit model for direct tunneling current in double-gate MOSFETs through a dielectric stack. Solid-State Electronics, 2012, 76, 19-24.	1.4	2

#	ARTICLE	IF	CITATIONS
235	Analysis and modeling of the gate leakage current in advanced nMOSFET devices with severe gate-to-drain dielectric breakdown. <i>Microelectronics Reliability</i> , 2012, 52, 1909-1912.	1.7	2
236	Impact of the forming and cycling processes on the electrical and physical degradation characteristics of HfO <sub>2</sub> -based resistive switching devices. <i>Thin Solid Films</i> , 2020, 706, 138027.	1.8	2
237	A simple, robust, and accurate compact model for a wide variety of complementary resistive switching devices. <i>Solid-State Electronics</i> , 2021, 185, 108083.	1.4	2
238	Limitations of oxide breakdown accelerated testing for reliability simulation. <i>Quality and Reliability Engineering International</i> , 1993, 9, 333-336.	2.3	1
239	Frequency dependence of degradation and breakdown of thin SiO <sub>2</sub> films. <i>Quality and Reliability Engineering International</i> , 1995, 11, 257-261.	2.3	1
240	Quantum Monte Carlo Simulation of Tunneling Devices Using Bohm Trajectories. <i>Physica Status Solidi (B): Basic Research</i> , 1997, 204, 404-407.	1.5	1
241	Two-step stress method for the dynamic testing of very thin (8 nm) SiO <sub>2</sub> films. <i>Microelectronics Reliability</i> , 1998, 38, 1127-1131.	1.7	1
242	Impact of MOS technological parameters on the detection and modeling of the soft breakdown conduction. , 0, , .		1
243	Quantum Simulation of Resonant Tunneling Diodes: a Reliable Approach Based on the Wigner Function Method. <i>Japanese Journal of Applied Physics</i> , 1999, 38, 2669-2674.	1.5	1
244	Comment on "New Current-Voltage Model for Surrounding-Gate Metal Oxide Semiconductor Field-Effect Transistors". <i>Japanese Journal of Applied Physics</i> , 2006, 45, 6057-6057.	1.5	1
245	Eigenstate fitting in the $k \cdot p$ method. <i>Journal of Computational Electronics</i> , 2007, 6, 195-198.	2.5	1
246	Monte Carlo simulations of nanometric devices beyond the "mean-field" approximation. <i>Journal of Computational Electronics</i> , 2008, 7, 197-200.	2.5	1
247	Pattern transfer optimization for the fabrication of arrays of silicon nanowires. <i>Microelectronic Engineering</i> , 2010, 87, 1479-1482.	2.4	1
248	Modeling the breakdown statistics of Al <sub>2</sub> O <sub>3</sub> /HfO <sub>2</sub> nanolaminates grown by atomic-layer-deposition. , 2011, , .		1
249	Generalized successive failure methodology for non-weibull distributions and its applications to SiO <sub>2</sub> or high-k/SiO <sub>2</sub> bilayer dielectrics and extrinsic failure mode. , 2012, , .		1
250	Temperature dependence of TDDB voltage acceleration in high- $\kappa$ /SiO <sub>2</sub> bilayers and SiO <sub>2</sub> gate dielectrics. , 2012, , .		1
251	Spatial statistics for micro/nanoelectronics and materials science. , 2012, , .		1
252	Study of the spatial distribution of breakdown spots in MOS devices in case of important edge effect anomalies. , 2012, , .		1

#	ARTICLE	IF	CITATIONS
253	Degradation and breakdown characteristics of Al/HfYOx/GaAs capacitors. Thin Solid Films, 2012, 520, 2956-2959.	1.8	1
254	Experimental evidence for a quantum wire state in HfO <sub>2</sub> -based VCM-RRAM. , 2013, , .		1
255	Field-effect control of breakdown paths in HfO <sub>2</sub> based MIM structures. Microelectronics Reliability, 2013, 53, 1346-1350.	1.7	1
256	Modeling of the output characteristics of advanced n-MOSFETs after a severe gate-to-channel dielectric breakdown. Microelectronic Engineering, 2013, 109, 322-325.	2.4	1
257	Effect of an ultrathin SiO <sub>2</sub> interfacial layer on the hysteretic current-voltage characteristics of CeOx-based metal-insulator-metal structures. Thin Solid Films, 2013, 533, 38-42.	1.8	1
258	Equivalent circuit model for the switching conduction characteristics of TiO <sub>2</sub> -based MIM structures. , 2014, , .		1
259	Modeling of the conduction characteristics of voltage-driven bipolar RRAMs including turning point effects. , 2015, , .		1
260	Function-fit model for the rate of conducting filament generation in constant voltage-stressed multilayer oxide stacks. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2017, 35, 01A108.	1.2	1
261	Statistical analysis of "Tail Bits" phenomena with defect clustering in RESET switching process of RRAM devices. , 2017, , .		1
262	Simple method for monitoring the switching activity in memristive cross-point arrays with line resistance effects. Microelectronics Reliability, 2019, 100-101, 113327.	1.7	1
263	An improved analytical model for the statistics of SET emergence point in HfO <sub>2</sub> memristive device. AIP Advances, 2019, 9, 025118.	1.3	1
264	Compact Model of the Nanoscale Gate-All-Around MOSFET. , 2005, , 321-326.		1
265	Breakdown of SiO <sub>2</sub> films in VLSI MOS structures. Vacuum, 1989, 39, 765-769.	3.5	0
266	On the oxide interface micro-roughness in MOS devices. Vacuum, 1989, 39, 771-774.	3.5	0
267	Simple STM theory. Vacuum, 1990, 41, 379-381.	3.5	0
268	Bohm trajectories and their potential use for the Monte Carlo simulation of resonant tunnelling diodes. Applied Surface Science, 1996, 102, 255-258.	6.1	0
269	Model-independent determination of the degradation dynamics of thin SiO <sub>2</sub> films. Microelectronics Reliability, 1999, 39, 891-895.	1.7	0
270	Evaluation of the Degradation Dynamics of Thin Silicon Dioxide Films Using Model-Independent Procedures. Materials Research Society Symposia Proceedings, 1999, 592, 7.	0.1	0



#	ARTICLE	IF	CITATIONS
271	Mesoscopic Transport in Broken Down Ultrathin SiO <sub>2</sub> Films. Materials Research Society Symposia Proceedings, 1999, 592, 113.	0.1	0
272	New global insight in ultra-thin oxide reliability using accurate experimental methodology and theoretical modeling. , 0, , .		0
273	Study of Electronic Transport in Tunneling Devices Using an Incoherent Superposition of Time Dependent Wave Packets. VLSI Design, 2001, 13, 145-148.	0.5	0
274	Study of Noise Properties in Nanoscale Electronic Devices Using Quantum Trajectories. Journal of Computational Electronics, 2002, 1, 43-48.	2.5	0
275	Quantum instantaneous current: application to nanoMOSFETs switched at very-high frequency. , 0, , .		0
276	Physics-Based Percolation Model of Oxide Breakdown. ECS Transactions, 2007, 8, 177-183.	0.5	0
277	High-frequency behavior of the Dattaâ€Das spin transistor. Applied Physics Letters, 2008, 93, 193502.	3.3	0
278	Towards a viable TDDDB reliability assessment methodology: From breakdown physics to circuit failure. , 2009, , .		0
279	Breakdown Statistics of Gate Dielectric Stacks. ECS Transactions, 2010, 27, 249-254.	0.5	0
280	Toy model for the progressive breakdown dynamics of ultrathin gate dielectrics. , 2011, , .		0
281	Electrical evidence of atomic-size effects in the conduction filament of RRAM. , 2012, , .		0
282	Electron transport in CeO <sub>2</sub> -based resistive switching devices. , 2012, , .		0
283	Modeling of the post-breakdown I <sub>on</sub> -V <sub>on</sub> characteristics of La <sub>2</sub> O <sub>3</sub> -based MOS transistors. , 2013, , .		0
284	Exploring the field-effect control of breakdown paths in lateral W/HfO <sub>2</sub> /W structures. , 2013, , .		0
285	Statistical approach to the RESET switching of the HfO <sub>2</sub> -based solid electrolyte memory. , 2013, , .		0
286	Single-parameter model for the post-breakdown conduction characteristics of HoTiO <sub>x</sub> -based MIM capacitors. Microelectronics Reliability, 2014, 54, 1707-1711.	1.7	0
287	Modeling of the major and minor I-V loops in La <sub>0.3</sub> Ca <sub>0.7</sub> MnO <sub>3</sub> films using asymmetric logistic hysterons. , 2015, , .		0
288	Modeling of the I-V and I-t characteristics of multiferroic BiFeO <sub>3</sub> layers. , 2015, , .		0

#	ARTICLE	IF	CITATIONS
289	The statistics of set time of oxide-based resistive switching memory. , 2016, , .		0
290	Volume Resistive Switching in Metallic Perovskite Oxides Driven by the Metal-Insulator Transition. Kluwer International Series in Electronic Materials: Science and Technology, 2022, , 289-310.	0.5	0
291	Application of artificial neural networks to the identification of weak electrical regions in large area MIM structures. Microelectronics Reliability, 2021, , 114312.	1.7	0
292	Simulation of Mesoscopic Devices with Bohm Trajectories and Wavepackets. , 2000, , 327-328.		0
293	Improving Electron Transport Simulation in Mesoscopic Systems by Coupling a Classical Monte Carlo Algorithm to a Wigner Function Solver. , 2000, , 330-331.		0
294	Failure Analysis of Large Area Pt/HfO <sub>2</sub> /Pt Capacitors Using Multilayer Perceptrons. , 2021, , .		0
295	SPICE Model for Complementary Resistive Switching Devices Based on Anti-Serially Connected Quasi-Static Memdiodes. Solid-State Electronics, 2022, , 108312.	1.4	0